



M02A430

IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Frank Jansen
S/N: 10/712,495
Filed: November 13, 2003
For: ATOMIC LAYER DEPOSITION PROCESS AND APPARATUS

Group No.: 1761
Examiner: H. E. Abramowitz
Atty. Dkt.: M02A430

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

Dear Sir:

In response to the Office Action dated May 4, 2005 applicants make the following remarks.

The Examiner has required a restriction between the following groups of claims:

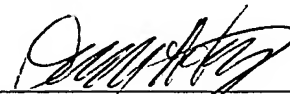
Group I, claims 1-10 classified in class 118, subclass 715; and
Group II, claims 11-20 classified in class 427, subclass 248.1.

Further, though not mentioned by the Examiner, it is noted that Group I relates to apparatus and Group II relates to methods.

Applicants provisionally elect, with traverse, Group II, claims 11-20 directed to methods of delivering precursor gas.

Applicants respectfully reserve the right to file divisional applications at a later date, on inventions not elected in this response.

Respectfully submitted,

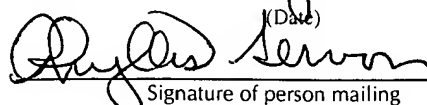
By: 
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Date: 23 May 2005
The BOC Group, Inc.
Legal Services-IP Dept.
575 Mountain Avenue
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450, on May 23, 2005

Phyllis Servon
Printed name of person signing this certificate


Signature of person mailing